

INFORMATION DISCLOSURE STATEMENT
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EXAMINER INITIALS	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
							YES	NO
<i>RK</i>		WO 94/11745	05/26/94	WIPO				
<i>RK</i>		EP 0 899 538	03/03/99	European Patent Office				
<i>RK</i>		EP 0 466 274	01/15/92	European Patent Office				
<i>RK</i>		EP 0 299 875	01/18/89	European Patent Office				
<i>RK</i>		DE 196 48 475	06/05/97	Germany				
<i>RK</i>		DE 43 01 420	06/24/93	Germany				
<i>RK</i>		8-15318	01/19/96	Japan				
<i>RK</i>		07199219	08/04/95	Japan			Abstract	
<i>RK</i>		01147374	06/09/89	Japan			Abstract	

RK		Fujii, et al., "Micropattern measurement with an atomic force microscope", <u>Journal of Vacuum Science & Technology: Part B</u> , Vol. 9, No. 2, pp. 666-669 (March/April 1991).
RK		Lee, et al., "High-Density Silicon Microprobe Arrays for LCD Pixel Inspection", <u>Institute of Electrical and Electronics Engineers</u> , pp. 429-434 (February 11, 1996).
RK		Hong, et al., "Design and Fabrication of a Monolithic High-Density Probe Card for High-Frequency On-Water Testing", <u>Institute of Electrical and Electronics Engineers</u> , pp. 289-292 (December 3, 1989).
RK		International Search Report for PCT/DK99/00391 (July 8, 1999)
		(completion date January 12, 2000)

~~Date Considered:~~

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